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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Tadahiro OHMI et al.  
Title: METHOD OF CLEANING SUBSTRATE PROCESSING APPARATUS  
Appl. No.: 10/555,668  
Filing Date: 12/21/2005  
Examiner: Nicole R. Blan  
Art Unit: 1792  
Confirmation No.: 9889

**AMENDMENT AND REPLY UNDER 37 C.F.R. 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated November 16, 2007, concerning the above-referenced patent application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this document.

**Remarks/Arguments** begin on page 5 of this document.

Please amend the application as follows: